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APPLICANT: TOYO METALLIZING CO LTD;

INVENTOR: MOCHIZUKI KIYOTO;

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TITLE

: FILM FORMING METHOD OF ANTIREFLECTION FILM ON PLASTIC FILM

ABSTRACT: PROBLEM TO BE SOLVED: To provide a method by which the effect of an ion-assist method can be obtd. as large as possible with good reproducibility when each layer of a multilayered antireflection film is continuously formed by an electron beam(EB) vapor deposition method by using and ion-assist method on a film which is continuously travelling.

> SOLUTION: At least two layers of films having different refractive indices are laminated on at least one surface of a plastic film which continuously travels by using a vapor deposition method by an electron bean heating method with ion-assist activating method with an ion gun in vacuum to form an antireflection film on a plastic film. In this method, each laver film is prevented from being exposed to an environment with lower vacuum degree than 10<sup>-2</sup>Torr between succeeding processes.

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